

## **AMENDMENTS TO THE CLAIMS**

This listing of claims will replace all prior versions, and listing, of claims in the application:

### **Listing of Claims**

1. (Currently Amended) Apparatus for applying fluid to a substrate movable in a principal direction of movement comprising:

a first slot nozzle capable of receiving the fluid from a fluid source and including a first slot nozzle outlet having a width adapted to extend transversely to the principal direction of movement for applying a first fluid film onto a side of the substrate to be coated,

a second slot nozzle having a second slot nozzle outlet and capable of receiving the fluid from the fluid source and applying a second fluid film onto a side of the substrate to be coated that lies opposite the side coated with the first fluid film,

first and second fluid passageways respectively communicating between said fluid source and said first and second slot nozzle outlets,

a first movable seal member positioned entirely outside of said first fluid passageway for adjusting the width of said first slot nozzle outlet transversely to the principal direction of movement of the substrate~~[[.]],~~ and

a second movable seal member positioned entirely outside of said second fluid passageway for adjusting the width of said second slot nozzle outlet transversely to the principal direction of movement of the substrate.

2. Canceled.

3. Canceled.

4. (Currently Amended) ~~The apparatus of claim 3, further comprising:~~

Apparatus for applying fluid to a substrate movable in a principal direction of movement comprising:

a first slot nozzle capable of receiving the fluid from a fluid source and including a first slot nozzle outlet having a width adapted to extend transversely to the principal direction of movement for applying a first fluid film onto a side of the substrate to be coated, and a fluid passageway communicating between said fluid source and said first slot nozzle outlet;

a first movable seal member disposed outside of said fluid passageway for adjusting the width of said first slot nozzle outlet transversely to the principal direction of movement of the substrate;

a second slot nozzle having a second slot nozzle outlet and capable of receiving the fluid from the fluid source and applying a second fluid film onto a side of the substrate to be coated that lies opposite the side coated with the first fluid film;

a second movable seal member for adjusting the width of said second slot nozzle outlet transversely to the principal direction of movement of the substrate; and

a third slot nozzle having a third slot nozzle outlet and capable of receiving the fluid from the fluid source and applying a third fluid film onto a third surface of the substrate.

5. (Canceled)

6 (Previously Presented) The apparatus of claim ~~[[2]]~~ 1 wherein said first and second slot nozzles are movably mounted for adjusting a gap between said first and second slot nozzles.

7. (Canceled)

8. (Previously Presented) The apparatus of claim 1, wherein said first nozzle outlet lies in a plane and said first movable seal member projects out of said plane in a direction of the substrate to be coated, in order to limit the thickness of the fluid film applied by said first slot nozzle onto the substrate.

9. (Currently Amended) The apparatus of claim 1, wherein said first slot nozzle includes a width and said fluid passageway extends across said width of said first slot nozzle and said first slot nozzle outlet lies in a plane, and the apparatus further comprises:

~~a fluid passageway extending across the width of said first slot nozzle,~~

a piston movable in said fluid passageway to seal said fluid passageway,

and

a sealing body extending within the plane of said first slot nozzle outlet, said piston and sealing body cooperating to adjust the width of said first slot nozzle outlet transversely to the principal direction of movement of the substrate.

10. (Previously Presented) The apparatus of claim 4, wherein said third slot nozzle outlet has a width and a gap is defined between said first and second slot nozzles, the width of said third slot nozzle outlet being limited by the gap between said first and second slot nozzles.

11. (Previously Presented) The apparatus of claim 4, further comprising:  
a clamping device for holding the movable substrate.

12. (Previously Presented) The apparatus of claim 11, further comprising:  
a lifting device configured to move said first, second and third slot nozzles toward and away from said clamping device.

13. (Canceled)

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